

AUTHOR INDEX

- Aberle, Armin G., 33, 173
 Adjallah, Y., 337
 Agert, Carsten, 273
 Agocs, E., 367
 Ahnood, Arman, 413
 Ait Fqir Ali-Guerry, Zahra, 209
 Akazawa, Muneki, 407
 Alexander, Duncan T.L., 349
 Anderson, C., 337
 Appel, Jesse, 93
 Appenzeller, W., 387
 Aryal, P., 267
 Attygalle, D., 267
 Aziz, Michael J., 291
- Babal, Pavel, 153
 Ballif, Christophe, 63, 123, 349, 423
 Banerjee, A., 3, 69, 81
 Barata, M., 417
 Beernink, K., 81
 Beglau, D., 3, 69
 Benaben, Patrick, 355
 Beneyton, Rémi, 209
 Bensahel, Daniel, 209
 Berry, Nathaniel E., 291
 Beyer, W., 135
 Bhattacharya, J., 99
 Birkmire, Robert, 93
 Biron, Rémi, 63
 Biswas, R., 99
 Bittkau, K., 57
 Blackwell, C., 285, 337
 Blayac, Sylvain, 355
 Bobela, D.C., 279
 Bodurtha, K., 337
 Bolman, B., 117
 Boniface, C., 141
 Brunets, Ihor, 179
- Cai, Bin, 297
 Carius, R., 57, 387
- Chaji, Reza, 413
 Chakravarty, N., 99
 Charpentier, C., 141
 Chen, Jian Z., 259
 Chen, Yung-Pei, 259
 Cheng, I-Chun, 259
 Cheng, P.H., 39, 129
 Chitu, A.M., 161, 197
 Chiu, I-Chung, 259
 Choi, Sung-Hwan, 235, 247
 Chu, V., 435
 Chuang, C.K., 129
 Chung, U.J., 161, 197
 Clark, Jessica, 291
 Collins, R.W., 267
 Conde, J.P., 435
 Congreve, Daniel, 229
 Costa, J., 223, 441
 Cunningham, Will, 291
 Cuony, Peter, 349
- Dahal, L.R., 267
 Dalal, V.L., 99
 Dalal, Vikram, 229
 Das, Ujjwal, 93
 DeMaggio, G., 81
 Deng, Y., 197
 Despeisse, Mathieu, 349, 423
 DiFranzo, Anthony, 291
 Dinca, Steluta, 329
 Drabold, D.A., 297
 Drahi, Etienne, 355
 Duchamp, Martial, 63
 Duda, Anna, 105
 Dunand, S., 423
 Dunin-Borkowski, Rafal, 63
 Dutartre, Didier, 209
- Emeraud, T., 141
 Escarré, Jordi, 63

- Fantoni, A., 417
 Fejfar, Antonín, 313
 Fernandes, M., 223, 417, 441
 Fields, Jeremy D., 279
 Franco, A., 423
 Fried, M., 267, 367

 Ganot, G.S., 161
 Garção, A.S., 441
 Gedvilas, L., 279
 Geißendörfer, Stefan, 273
 Geng, Xinhua, 111, 393
 Gordijn, A., 387
 Guha, Subhendu, 3, 69, 81, 329

 Han, Min-Koo, 235, 241, 247, 253
 Haug, Franz-Josef, 63, 123
 Hayashi, Hidetaka, 217
 Hegedus, Steve, 93
 Hidayat, Hidayat, 33, 173
 Higashi, Seiichiro, 407
 Hoffmann, A., 57
 Hsu, C.H., 15, 39, 129
 Hsu, H.J., 15, 39
 Hu, Q., 197
 Huang, Jung-Jie, 259
 Huang, Qian, 185, 191
 Huang, Z., 267
 Huet, Karim, 141, 209
 Hülsbeck, M., 387
 Hutchinson, David, 291

 Im, James S., 161, 197
 Isabella, Olindo, 117, 153

 Jäger, Klaus, 153
 Jarron, P., 423
 Johnson, E.V., 141
 Joskowiak, A., 435
 Juhasz, G., 267

 Kakalios, James, 285, 337
 Kanayama, Toshihiko, 307, 361
 Karmali, A., 223
 Kherani, Nazir P., 399

 Kim, Sun-Jae, 253
 Kiriluk, K.G., 279
 Kittisontirak, Songkiate, 147
 Klapetek, Petr, 313
 Kočka, Jan, 313
 Köhler, F., 387
 Kondo, Michio, 21
 Korte, L., 323
 Kortshagen, U., 337
 Kovalgin, Alexey Y., 179
 Koyanagi, Shunki, 407
 Krč, J., 117
 Krumrey, Michael, 349
 Kuk, Seung-Hee, 241
 Kumagai, Kyoko, 217
 Kumar, A., 173
 Kuo, Yue, 167
 Kwok, Hoi Sing, 185, 191
 Kwon, Jang-Yeon, 247, 253

 Ledinský, Martin, 313
 Lee, Benjamin G., 105
 Lee, C.Y., 129
 Lee, Catherine S., 197
 Lee, Jeong-Soo, 247
 Lee, Soo-Yeon, 253
 Lee, Woo-Geun, 253
 Lee, Young Wook, 247, 253
 Leendertz, C., 323
 Lennartz, D., 135
 Leong, Keith R., 399
 Lerat, J.F., 141
 Li, He, 185, 191
 Li, Juan, 185, 191
 Li, T., 197
 Liang, S.W., 39
 Limanov, A.B., 161, 197
 Limmanee, Amornrat, 147
 Lin, Chen-Han, 167
 Lin, Y.P., 39
 Liu, F., 3, 81
 Liu, P., 117
 Löfgren, Linus, 349
 Long, Qi, 329
 Lord, K., 81

- Louro, P., 223, 417, 441, 449
 Lu, Guo-Neng, 209
 Luo, Chong, 185, 191
- Major, C., 267
 Marending, Michael, 349
 Matsuda, Akihisa, 375
 Matsui, Takuya, 21
 Matsushita, Y., 361
 McGahan, Christina, 291
 Meier, M., 387
 Meng, Zhiguo, 185, 191
 Middy, A.R., 45
 Miyazaki, Takehide, 307, 361
 Mo, Yeon-Gon, 235
 Mück, A., 387
 Müllejans, Harald, 75
 Muthmann, S., 387
- Nagashima, So, 217
 Naqavi, A., 123
 Nassiopoulou, A.G., 367
 Nathan, Arokia, 413
 Nemeth, A., 267
 Nemeth, Bill, 105
 Noack, Max, 229
 Noborisaka, Mayui, 217
 Normandon, Philippe, 209
- Oesterlin, Peter, 179
 Okamoto, Hiroaki, 375
 Omori, K., 161
 Owen, J., 57
- Pahud, Céline, 63
 Park, Sang-Geun, 241
 Pattnaik, S., 99
 Pecz, B., 267
 Persans, Peter D., 291
 Peterson, Hannah, 291
 Petrik, P., 267, 367
 Pietka, G., 3, 69, 81
 Piromjit, Channarong, 147
 Polgar, O., 267
 Powolny, F., 423
- Pravettoni, Mauro, 51
 Prazeres, D.M.F., 435
 Prod'homme, P., 141
 Prunici, P., 135
- Rangarajan, Balaji, 179
 Rech, B., 323
 Recht, Daniel, 291
 Riesen, Y., 423
 Roca i Cabarrocas, P., 141
- Sada, Chitose, 375
 Said, Aurore J., 291
 Salupo, C., 267
 Sameshima, K., 361
 Santbergen, Rudi, 153
 Sazonov, A., 455
 Schiff, Eric A., 45, 329
 Schmidt, M., 323
 Schmitz, Jurriaan, 179
 Schmitz, R., 387
 Schropp, R.E.I., 9
 Schulze, T.F., 323
 Shengzhi, Xu, 185
 Shirakura, Akira, 217
 Shyam, Ashutosh, 229
 Silva, T., 449
 Slafer, D., 99
 Sobajima, Yasushi, 375
 Söderström, Karin, 63, 123
 Solntsev, Serge, 153
 Sriprapha, Kobsak, 147
 Sritharathikhun, Jaran, 147
 Stiebig, H., 135
 Su, T., 3, 69
 Sun, Jian, 393
 Sun, Ted, 105
 Suzuki, Tetsuya, 217
- Taylor, P.C., 279
 Thompson, M.O., 197
 Trask, J., 337
 Tsai, C.C., 15, 39, 129
 Tzamalīs, Georgios, 75

- Uchida, Noriyuki, 307, 361
Ueda, Naoharu, 217
- van Dam, L.M., 9
van Sark, W.G.J.H.M., 9
Vetushka, Aliaksei, 313
Vieira, M., 223, 417, 441, 449, 455
Vieira, M.A., 223, 417, 441, 449
Virtuani, Alessandro, 51
von Maydell, Karsten, 273
Vygranenko, Y., 455
- Wang, C.M., 15
Wang, Guanghong, 111, 393
Wang, Haorong, 105
Wang, K., 203
Wang, Qi, 105, 167
Warrender, Jeffrey M., 291
Wei, Changchun, 393
Widenborg, Per I., 33, 173
Wienkes, L.R., 285, 337
Wong, K.H., 203
Woo, Jong-Seok, 241
- Worrel, C., 81
Wu, Chunya, 185
Wyrsh, N., 423
- Xiong, Shaozhen, 111, 185, 191, 393
Xu, Shengzhi, 111, 191, 393
Xu, Yueqin, 105
- Yan, Baojie, 3, 69, 329
Yang, Jeff, 3, 69, 81, 329
Yoon, Kap-Soo, 253
Yue, G., 69
- Zeman, M., 117
Zeman, Miro, 153
Zhang, Lulu, 93
Zhang, Xiaodan, 111, 393
Zhao, Ying, 111, 393
Zheng, Xinxia, 393
Zhu, Minghao, 167
Zixuan, Qiu, 173
Zlámál, Jakub, 313
Zukotynski, Stefan, 399

SUBJECT INDEX

- absorption, 63
 Al, 203
 alloy, 147
 amorphous, 15, 39, 81, 93, 105, 123,
 197, 229, 267, 297, 307, 323,
 329, 337, 417, 423, 435
 annealing, 135, 191
 B, 297
 chemical vapor deposition (CVD)
 (deposition), 111, 179
 cluster assembly, 361
 crystal growth, 161, 167, 393, 407
 crystalline, 197
 defects, 51, 185, 279, 329
 devices, 111, 223, 413, 441, 449
 display, 241, 253
 dopant, 173
 elastic properties, 253
 electrical properties, 285
 electronic material, 167
 electronic structure, 323
 energy generation, 413
 energy storage, 413
 Ge, 21, 229
 grain size, 179
 Hall effect, 173
 hardness, 217
 ion-implantation, 209
 laser ablation, 361
 laser annealing, 141, 161, 179, 197,
 209, 291
 luminescence, 279
 mass spectroscopy, 399
 microstructure, 313, 387
 microwave heating, 355
 nanostructure, 285, 337, 367, 393
 optical properties, 75, 267, 367
 optoelectronic, 99, 117, 223, 337,
 417, 441, 449
 oxide, 141, 247
 passivation, 33, 185, 209, 297
 phase transformation, 191
 photoconductivity, 291
 photovoltaic, 3, 9, 15, 21, 33, 45, 51,
 69, 75, 81, 93, 99, 105, 111,
 117, 123, 129, 153, 267, 349,
 355, 375
 plasma-enhanced CVD (PECVD)
 (chemical reaction), 15, 173
 plasma-enhanced CVD (PECVD)
 (deposition), 39, 93, 129, 217,
 259, 375, 387, 393, 399, 455
 polycrystal, 185, 191, 203, 235, 367
 polymer, 45
 Raman spectroscopy, 387
 rapid solidification, 407
 scanning electron microscopy
 (SEM), 117
 scanning probe microscopy (SPM),
 57, 313
 semiconducting, 247
 sensor, 223, 417, 423, 435, 449, 455
 Si, 3, 9, 21, 33, 39, 45, 69, 81, 99,
 105, 123, 129, 135, 147, 153,
 203, 229, 235, 241, 259, 273,
 279, 285, 291, 307, 313, 323,
 329, 349, 375, 399, 407, 423, 435

simulation, 153, 273, 307, 441

sintering, 355

texture, 57, 63

thin film, 3, 9, 51, 57, 63, 69, 75, 135,

147, 161, 167, 217, 235, 241,

253, 259, 273, 349, 361, 455

Ti, 247

transparent conductor, 141